

DOCKET NO: 296431US2PCT

IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF :
HISAO IGARASHI, ET AL. : ATTN: APPLICATION DIVISION
SERIAL NO: NEW U.S. PCT APPLICATION :
(BASED ON PCT/JP05/06108)
FILED: HERewith :
FOR: PROBE APPARATUS, WAFER :
INSPECTING APPARATUS
PROVIDED WITH THE PROBE
APPARATUS AND WAFER
INSPECTING METHOD

PRELIMINARY AMENDMENT

COMMISSIONER FOR PATENTS
ALEXANDRIA, VIRGINIA 22313

SIR:

Prior to a first examination on the merits, please amend the above-identified application as follows:

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page 4 of this paper.

Remarks/Arguments begin on page 9 of this paper.